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CLAIM AMENDMENTS

1. (canceled)
2. (currently amended) A method in accordance with claim 1 3 wherein said substrate comprises at least one of the group consisting of a nanowire, a cantilever, a conductive micro/nanometer structure, and a wafer.
3. (currently amended) A method ~~in accordance with claim 1~~ wherein said ~~depositing step~~ further comprises of growing a carbon nanostructure comprising the steps of:
 - a. providing a substrate having thereon at least two electrically conductive nanostructures spaced no more than about 50 μm apart; and
 - b. depositing a catalyst dot on at least one of said nanostructures by electric field-directed, programmable, pulsed electrolytic metal deposition; and
 - c. growing a carbon nanostructure on said catalyst dot.
4. (currently amended) A method in accordance with claim 1 3 wherein said growing step further comprises a plasma-enhanced chemical vapor deposition method.
5. (currently amended) A method in accordance with claim 1 3 wherein said carbon nanostructure is grown in a direction perpendicular to a surface of said substrate.
6. (currently amended) A method in accordance with claim 1 3 wherein said carbon nanostructure is grown on a flat-tipped surface having an upward-facing catalyst dot.

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7. (currently amended) A method in accordance with claim ~~4~~ 3 wherein said carbon nanostructure further comprises at least one of the group consisting of a single-wall carbon nanotube, a multi-wall carbon nanotube, a carbon nanofiber, a carbon needle, and a carbon whisker.
8. (currently amended) A method in accordance with claim ~~4~~ 3 wherein said depositing step further comprises an automated process.
9. (currently amended) A method in accordance with claim ~~4~~ 3 wherein said growing step further comprises an automated process.
10. (canceled)
11. (canceled)
12. (canceled)
13. (canceled)